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APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.
10/812,768	03/30/2004	Jung-Hun Seo	5649-1263	4965
7590	03/23/2006		EXAMINER	
Laura M. Kelley Myers Bigel Sibley & Sajovec, P.A. P.O. Box 37428 Raleigh, NC 27627				MOORE, KARLA A
			ART UNIT	PAPER NUMBER
			1763	

DATE MAILED: 03/23/2006

Please find below and/or attached an Office communication concerning this application or proceeding.

Office Action Summary	Application No.	Applicant(s)
	10/812,768	SEO ET AL.
	Examiner Karla Moore	Art Unit 1763

-- The MAILING DATE of this communication appears on the cover sheet with the correspondence address --

Period for Reply

A SHORTENED STATUTORY PERIOD FOR REPLY IS SET TO EXPIRE 3 MONTH(S) OR THIRTY (30) DAYS, WHICHEVER IS LONGER, FROM THE MAILING DATE OF THIS COMMUNICATION.

- Extensions of time may be available under the provisions of 37 CFR 1.136(a). In no event, however, may a reply be timely filed after SIX (6) MONTHS from the mailing date of this communication.
- If NO period for reply is specified above, the maximum statutory period will apply and will expire SIX (6) MONTHS from the mailing date of this communication.
- Failure to reply within the set or extended period for reply will, by statute, cause the application to become ABANDONED (35 U.S.C. § 133). Any reply received by the Office later than three months after the mailing date of this communication, even if timely filed, may reduce any earned patent term adjustment. See 37 CFR 1.704(b).

Status

- 1) Responsive to communication(s) filed on 25 January 2006.
- 2a) This action is FINAL. 2b) This action is non-final.
- 3) Since this application is in condition for allowance except for formal matters, prosecution as to the merits is closed in accordance with the practice under *Ex parte Quayle*, 1935 C.D. 11, 453 O.G. 213.

Disposition of Claims

- 4) Claim(s) 1-30 is/are pending in the application.
- 4a) Of the above claim(s) 16-30 is/are withdrawn from consideration.
- 5) Claim(s) _____ is/are allowed.
- 6) Claim(s) 1-15 is/are rejected.
- 7) Claim(s) _____ is/are objected to.
- 8) Claim(s) _____ are subject to restriction and/or election requirement.

Application Papers

- 9) The specification is objected to by the Examiner.
- 10) The drawing(s) filed on 30 March 2004 is/are: a) accepted or b) objected to by the Examiner.
Applicant may not request that any objection to the drawing(s) be held in abeyance. See 37 CFR 1.85(a).
Replacement drawing sheet(s) including the correction is required if the drawing(s) is objected to. See 37 CFR 1.121(d).
- 11) The oath or declaration is objected to by the Examiner. Note the attached Office Action or form PTO-152.

Priority under 35 U.S.C. § 119

- 12) Acknowledgment is made of a claim for foreign priority under 35 U.S.C. § 119(a)-(d) or (f).
- a) All b) Some * c) None of:
 1. Certified copies of the priority documents have been received.
 2. Certified copies of the priority documents have been received in Application No. _____.
 3. Copies of the certified copies of the priority documents have been received in this National Stage application from the International Bureau (PCT Rule 17.2(a)).

* See the attached detailed Office action for a list of the certified copies not received.

Attachment(s)

- 1) Notice of References Cited (PTO-892)
- 2) Notice of Draftsperson's Patent Drawing Review (PTO-948)
- 3) Information Disclosure Statement(s) (PTO-1449 or PTO/SB/08)
Paper No(s)/Mail Date 0304,0505.
- 4) Interview Summary (PTO-413)
Paper No(s)/Mail Date. _____.
- 5) Notice of Informal Patent Application (PTO-152)
- 6) Other: _____.

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DETAILED ACTION

Election/Restrictions

1. Applicant's election of Group I (claims 1-15) in the reply filed on 25 January 2005 is acknowledged. Because applicant did not distinctly and specifically point out the supposed errors in the restriction requirement, the election has been treated as an election without traverse (MPEP § 818.03(a)).
2. Claims 16-30 are withdrawn from further consideration pursuant to 37 CFR 1.142(b) as being drawn to a nonelected invention, there being no allowable generic or linking claim.

Claim Rejections - 35 USC § 102

3. The following is a quotation of the appropriate paragraphs of 35 U.S.C. 102 that form the basis for the rejections under this section made in this Office action:

A person shall be entitled to a patent unless –

- (b) the invention was patented or described in a printed publication in this or a foreign country or in public use or on sale in this country, more than one year prior to the date of application for patent in the United States.
- (e) the invention was described in (1) an application for patent, published under section 122(b), by another filed in the United States before the invention by the applicant for patent or (2) a patent granted on an application for patent by another filed in the United States before the invention by the applicant for patent, except that an international application filed under the treaty defined in section 351(a) shall have the effects for purposes of this subsection of an application filed in the United States only if the international application designated the United States and was published under Article 21(2) of such treaty in the English language.

4. Claims 1-8 and 10-13 are rejected under 35 U.S.C. 102(e) as being anticipated by U.S. Patent Publication No. 2004/0009678 A1 to Asai et al.

5. Asai et al. disclose a metal deposition apparatus comprising: a first processing chamber () capable of being configured for holding a semiconductor substrate therein and for processing a barrier metal layer thereon; a second processing chamber capable of being configured for holding the semiconductor substrate therein and for forming an upper metal layer thereon; and a transfer chamber () isolated from an oxygen atmosphere and connected to the first processing chamber and the second processing chamber, the transfer chamber configured to transfer the semiconductor substrate between the first processing chamber and the second processing chamber.

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6. With respect to Applicant's numerous intended use recitations in apparatus claims 1-15, Examiner notes that the courts have ruled that a "recitation with respect to the manner in which a claimed apparatus is intended to be employed does not differentiate the claimed apparatus from a prior art apparatus" if the prior art apparatus teaches all the structural limitations of the claim. Ex parte Masham, 2 USPQ2d 1647 (Bd. Pat. App. & Inter. 1987)

7. With respect to claim 2, Asai et al. teach the apparatus can be used for the recited intended method.

8. With respect to claims 3-4, the first processing chamber is capable of MOCVD and of being supplied with a MOCVD precursor (Figure 1, 9).

9. With respect to claims 5-8, the first processing chamber is configured for flushing using a showerhead (Figure 1, 6) and a halogen precursor such as TiCl₄ ().

10. With respect to claim 10, the apparatus comprises a transfer robot (41) in the transfer chamber.

11. With respect to claim 11, the second processing chamber can be a CVD, ALD or PVD chamber (paragraph 204).

12. With respect to claim 12, the apparatus comprises at least one loadlock chamber (42).

13. With respect to claim 13, Asai et al. teach that it is known in the art to provide a heating chamber as one of the processing chambers in a cluster tool (paragraph 12).

14. Claims 1, 9 and 15 are rejected under 35 U.S.C. 102(b) as being anticipated by U.S. Patent 5,740,034 to Saeki.

15. Saeki discloses a metal deposition apparatus comprising: a first processing chamber (Figure 1, 4B; column 8; rows 18-46) capable of being configured for holding a semiconductor substrate therein and for processing a barrier metal layer thereon; a second processing chamber (4C) capable of being configured for holding the semiconductor substrate therein and for forming an upper metal layer thereon; and a transfer chamber (2) isolated from an oxygen atmosphere and connected to the first processing chamber and the second processing chamber, the transfer chamber configured to transfer the semiconductor substrate between the first processing chamber and the second processing chamber.

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16. With respect to claim 9, gate valves (G7 and G8) are provided between each of the processing chambers and the transfer chamber.
17. With respect to claim 15, an alignment chamber (30) with an optical sensor may also be provided connected to the processing chamber.

Claim Rejections - 35 USC § 103

18. The following is a quotation of 35 U.S.C. 103(a) which forms the basis for all obviousness rejections set forth in this Office action:

(a) A patent may not be obtained though the invention is not identically disclosed or described as set forth in section 102 of this title, if the differences between the subject matter sought to be patented and the prior art are such that the subject matter as a whole would have been obvious at the time the invention was made to a person having ordinary skill in the art to which said subject matter pertains. Patentability shall not be negatived by the manner in which the invention was made.

19. This application currently names joint inventors. In considering patentability of the claims under 35 U.S.C. 103(a), the examiner presumes that the subject matter of the various claims was commonly owned at the time any inventions covered therein were made absent any evidence to the contrary. Applicant is advised of the obligation under 37 CFR 1.56 to point out the inventor and invention dates of each claim that was not commonly owned at the time a later invention was made in order for the examiner to consider the applicability of 35 U.S.C. 103(c) and potential 35 U.S.C. 102(e), (f) or (g) prior art under 35 U.S.C. 103(a).

20. Claim 14 is rejected under 35 U.S.C. 103(a) as being unpatentable over Saeki as applied above and as further applied below.

21. Saeki discloses the invention substantially as claimed and as described above, including teaching a cooling processing chamber (24; column 9, rows 32-40) with a circulation conduit and
22. However, Saeki fails to specifically teach the cooling means as a circulation conduit.
23. Providing a circulating cooling conduit in a substrate support means is well known in the art.
24. It would have been obvious to one of ordinary skill in the art to provide a circulation conduit as the cooling means in Saeki.

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Conclusion

Any inquiry concerning this communication or earlier communications from the examiner should be directed to Karla Moore whose telephone number is 571.272.1440. The examiner can normally be reached on Monday-Friday, 9:00 am-6:00 pm.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Parviz Hassanzadeh can be reached on 571.272.1435. The fax phone number for the organization where this application or proceeding is assigned is 571-273-8300.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see <http://pair-direct.uspto.gov>. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).



Karla Moore
Patent Examiner
Art Unit 1763
18 March 2006